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## EE C247B - ME C218 Introduction to MEMS Design Spring 2019

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**Lecture Module 11: Equivalent Circuits I**

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## Lecture Outline

- Reading: Senturia, Chpt. 5
- Lecture Topics:
  - ↪ Lumped Mass
  - ↪ Lumped Stiffness
  - ↪ Lumped Damping
  - ↪ Lumped Mechanical Equivalent Circuits
  - ↪ Electromechanical Analogies

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## Lumped Parameter Mechanical Equivalent Circuit

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## Equivalent Dynamic Mass

- Once the mode shape is known, the lumped parameter equivalent circuit can then be specified
- Determine the equivalent mass at a specific location  $x$  using knowledge of kinetic energy and velocity

Maximum Kinetic Energy →  $\frac{1}{2} \rho A \int_0^L V^2(x) dx$

Equivalent Mass =  $M_{eq\ x} = \frac{K.E.}{\frac{1}{2} V_x^2} = \frac{\frac{1}{2} \rho A \int_0^L V^2(x) dx}{\frac{1}{2} V_x^2}$

Maximum Velocity @ location  $x$  →  $\frac{1}{2} V_x^2$

Maximum Velocity Function →  $\frac{1}{2} V^2(x)$

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### Equivalent Dynamic Mass

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- For the folded-beam structure, we've already determined the maximum kinetic energy
- And in our resonance frequency analysis, we've already determined expressions for velocity

**Location on the Truss:**

$$M_{eq(truss)} = \frac{KE_{max}}{\frac{1}{2} V_{truss}^2} = \frac{\omega_0^2 x_0^2 (\frac{1}{2}) [M_t + \frac{1}{4} M_s + \frac{12}{35} M_b]}{\frac{1}{2} \omega_0^2 x_0^2}$$

$$\therefore M_{eq(truss)} = 4 [M_t + \frac{1}{4} M_s + \frac{12}{35} M_b]$$

**Location on the Shuttle:**

$$M_{eq(shuttle)} = \frac{KE_{max}}{\frac{1}{2} V_{shuttle}^2} = \frac{\omega_0^2 x_0^2 (\frac{1}{2}) [M_s + \frac{1}{4} M_t + \frac{12}{35} M_b]}{\frac{1}{2} \omega_0^2 x_0^2}$$

$$\therefore M_{eq(shuttle)} = M_s + \frac{1}{4} M_t + \frac{12}{35} M_b$$

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### Equivalent Dynamic Stiffness & Damping

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- Stiffness then follows directly from knowledge of mass and resonance frequency

$$\omega_0 = \sqrt{\frac{K_{eq}(x)}{M_{eq}(x)}} \rightarrow K_{eq}(x) = \omega_0^2 M_{eq}(x) \quad \Rightarrow \text{large equiv. mass \& large stiffness go hand-in-hand}$$

- And damping also follows readily from knowledge of Q or other loss measurands

$$Q = \frac{\omega_0 M_{eq}(x)}{C_{eq}(x)} \rightarrow C_{eq}(x) = \frac{\omega_0 M_{eq}(x)}{Q} = \frac{\sqrt{K_{eq}(x) M_{eq}(x)}}{Q}$$

*(Note: C<sub>eq</sub>(x) is labeled as damping)*

- With mass, stiffness, and damping  $\Rightarrow$  lumped parameter equivalent circuit

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### Get Potential Energy & Frequency

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**Parameters:**

- Q = 100k
- W = 2µm
- L = 100µm
- h = thickness = 2µm
- Area = 4,000µm<sup>2</sup>

**Truss Properties:**

- $K_{eq}(truss) = 19.2 \text{ N/m}$
- $M_{eq}(truss) = 8.64 \times 10^{-11} \text{ kg}$
- $C_{eq}(truss) = 4.08 \times 10^{-10} \text{ kg/s}$

**Shuttle Properties:**

- $K_{eq}(shuttle) = 4.8 \text{ N/m}$
- $M_{eq}(shuttle) = 2.16 \times 10^{-11} \text{ kg}$
- $C_{eq}(shuttle) = 1.02 \times 10^{-10} \text{ kg/s}$

**Equivalent Circuit:**

$K_{eq} = M_{eq} = C_{eq} = \infty$

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### Electromechanical Analogies

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**Equation of Motion:**

$$m_{eq} \ddot{x} + C_{eq} \dot{x} + k_{eq} x = F(t)$$

$\Rightarrow$  using phasor concepts:

$$F = j\omega m_{eq} \dot{x} + \frac{k_{eq}}{j\omega} x + C_{eq} \dot{x}$$

$\Rightarrow$  by analogy:

$$\begin{matrix} F \rightarrow N & m_{eq} \rightarrow l_x & C_{eq} \rightarrow r_x \\ \dot{x} \rightarrow \dot{q} & k_{eq} \rightarrow \frac{1}{c_x} & \end{matrix}$$

**Parameter Relationships in the Current Analogy:**

$$v(t) = V \cos(\omega t) \rightarrow i(t) = I \cos(\omega t)$$

$$\frac{V}{I} = j\omega l_x + \frac{1}{j\omega c_x} + r_x$$

$$N = j\omega l_x i + \frac{1}{j\omega} \dot{q} + r_x i$$

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### Electromechanical Analogies (cont)

• Mechanical-to-electrical correspondence in the current analogy:

Mechanical Variable	Electrical Variable
Damping, $c$	Resistance, $R$
Stiffness <sup>-1</sup> , $k^{-1}$	Capacitance, $C$
Mass, $m$	Inductance, $L$
Force, $f$	Voltage, $V$
Velocity, $v$	Current, $I$

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### Bandpass Biquad Transfer Function

$F = j\omega m_{eq} \dot{x} + \frac{k_{eq}}{j\omega} x + c_{eq} \dot{x}$   
 $\Rightarrow$  Converting to full phasor form:  
 $F = (j\omega)(j\omega x) m_{eq} + \frac{k_{eq}}{j\omega} x + c_{eq} (j\omega x)$   
 $\frac{X}{F}(j\omega) = \frac{1}{k_{eq}} \left[ -\omega^2 \frac{m_{eq}}{k_{eq}} + 1 + j \frac{c_{eq}\omega}{k_{eq}} \right]^{-1} = \frac{1}{k_{eq}} \left[ 1 - \left(\frac{\omega}{\omega_0}\right)^2 + j \frac{\omega}{Q\omega_0} \right]^{-1}$   
 $\left[ \frac{k_{eq}}{m_{eq}} = \omega_0^2, Q = \frac{m_{eq}\omega_0}{c_{eq}} = \frac{k_{eq}}{\omega_0 c_{eq}} \rightarrow \frac{k_{eq}}{c_{eq}} = Q\omega_0 \right]$

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### 3CC 3λ/4 Bridged μMechanical Filter

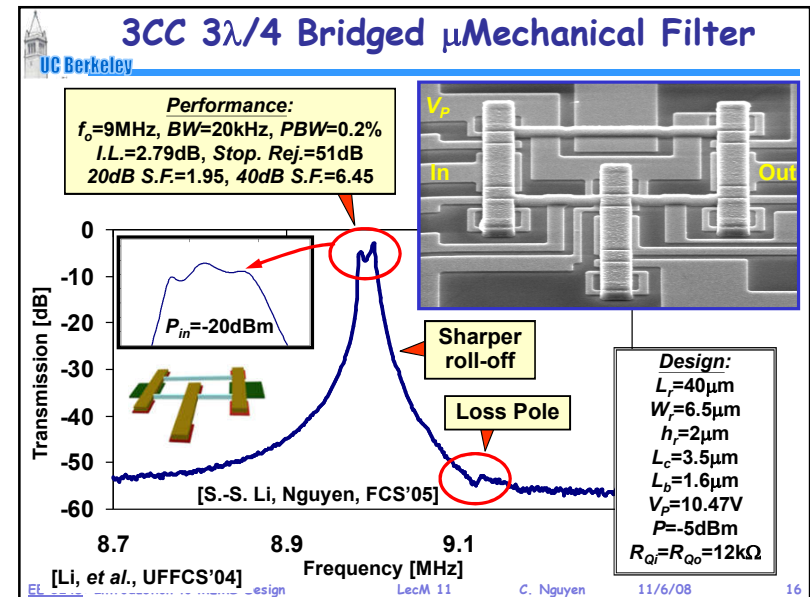
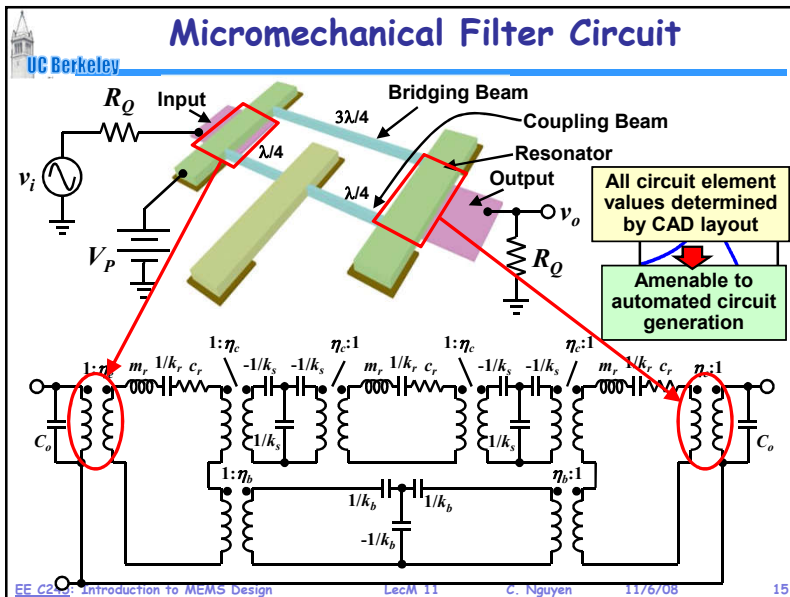
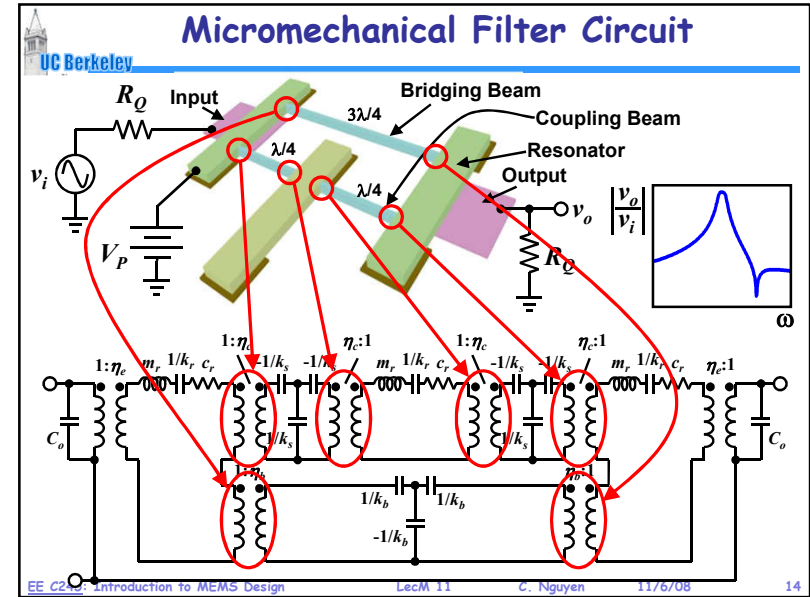
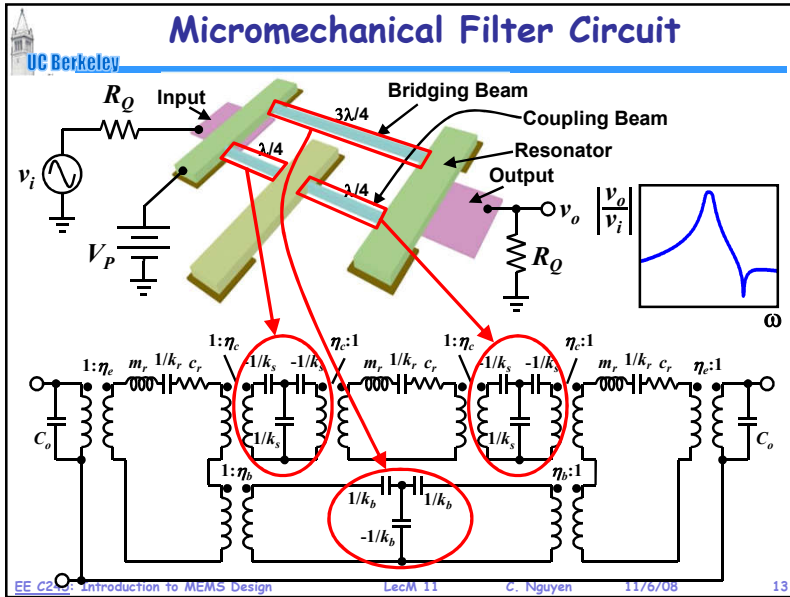
Performance:  
 $f_0 = 9\text{MHz}$ ,  $BW = 20\text{kHz}$ ,  $PBW = 0.2\%$   
 $I.L. = 2.79\text{dB}$ ,  $Stop. Rej. = 51\text{dB}$   
 $20\text{dB S.F.} = 1.95$ ,  $40\text{dB S.F.} = 6.45$

Design:  
 $L_r = 40\mu\text{m}$   
 $W_r = 6.5\mu\text{m}$   
 $h_r = 2\mu\text{m}$   
 $L_c = 3.5\mu\text{m}$   
 $L_b = 1.6\mu\text{m}$   
 $V_p = 10.47\text{V}$   
 $P = -5\text{dBm}$   
 $R_{Qi} = R_{Qo} = 12\text{k}\Omega$

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### Micromechanical Filter Circuit

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## Beam Resonator Equivalent Circuits (Pretty Much the Same Stuff)

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## Equivalent Dynamic Mass

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- Determine the equivalent mass at a specific location  $x$  using knowledge of kinetic energy and velocity

Maximum Kinetic Energy  $\rightarrow$   $\frac{1}{2} \rho A \int_0^l V^2(x) dx$

Equivalent Mass =  $M_{eq\ x} = \frac{K.E.}{\frac{1}{2} V_x^2} = \frac{\frac{1}{2} \rho A \int_0^l V^2(x) dx}{\frac{1}{2} V_x^2}$

Maximum Velocity @ location  $x \rightarrow$   $\frac{1}{2} V_x^2$       Density  $\rightarrow$   $\frac{1}{2} \rho A \int_0^l V^2(x) dx$       Maximum Velocity Function  $\rightarrow$   $\frac{1}{2} V_x^2$

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## Equivalent Dynamic Mass

- We know the mode shape, so we can write expressions for displacement and velocity at resonance

Displacement:  $u(x) = B [S(\cosh kx + \cos kx) + (\sinh kx + \sin kx)]$ ,  $S = \frac{A}{B}$

$[V(x) = \omega u(x)] \Rightarrow M_{eq}(x) = \frac{KE_{max}}{\frac{1}{2} [V(x)]^2} = \frac{\frac{1}{2} \rho A \int_0^l \omega^2 [u(x')]^2 dx'}{\frac{1}{2} \omega^2 [u(x)]^2}$

$$M_{eq}(x) = \frac{\rho A \int_0^l B^2 [S(\cosh kx' + \cos kx') + (\sinh kx' + \sin kx')]^2 dx'}{B^2 [S(\cosh kx + \cos kx) + (\sinh kx + \sin kx)]^2}$$

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## Equivalent Dynamic Stiffness & Damping

- Stiffness then follows directly from knowledge of mass and resonance frequency

$$\omega_0 = \sqrt{\frac{K_{eq}(x)}{M_{eq}(x)}} \rightarrow K_{eq}(x) = \omega_0^2 M_{eq}(x)$$

- And damping also follows readily

$$Q = \frac{\omega_0 M_{eq}(x)}{C_{eq}(x)} \rightarrow C_{eq}(x) = \frac{\omega_0 M_{eq}(x)}{Q} = \frac{\sqrt{K_{eq}(x) M_{eq}(x)}}{Q}$$

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**Equivalent Lumped Mechanical Circuit**

Location  $x$

$K_{eq}(x) = \omega_o^2 M_{eq}(x)$

$C_{eq}(x) = \frac{\omega_o M_{eq}(x)}{Q}$

$M_{eq}(x) = \frac{\rho A \int_0^l [u(x')]^2 dx'}{[u(x)]^2}$

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**Equivalent Lumped Mechanical Circuit**

Example: Polysilicon w/  $l=14.9\mu\text{m}$ ,  
 $W=6\mu\text{m}$ ,  $h=2\mu\text{m} \rightarrow 70\text{ MHz}$

$K_{eq}(0) = 19,927\text{ N/m}$

$M_{eq}(0) = 1.03 \times 10^{-13}\text{ kg}$

$C_{eq}(0) = 5.66 \times 10^{-9}\text{ kg/s}$

$K_{eq}(l/2) = 53,938\text{ N/m}$

$M_{eq}(l/2) = 2.78 \times 10^{-13}\text{ kg}$

$C_{eq}(l/2) = 1.53 \times 10^{-8}\text{ kg/s}$

$K_{eq}(\text{node}) = \infty$

$M_{eq}(\text{node}) = \infty$

$C_{eq}(\text{node}) = \infty$

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